

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) An apparatus for outputting a laser beam comprising:
a laser beam source;
laser beam diameter adjusting means for adjusting a diameter of a beam incident from said laser beam source;
laser beam reflecting direction controlling means for controlling a reflecting direction of the beam incident from said laser beam diameter adjusting means; and
recording means for recording information data in accordance with said diameter of ~~the said~~ beam incident from said laser beam ~~reflection~~ reflecting direction controlling means.
2. (Currently Amended) The apparatus according to claim 1, wherein said laser beam diameter adjusting means comprises:
a piezoelectric/electrostrictive film ~~type~~ element comprising:
_____ a substrate;
_____ a piezoelectric/electrostrictive operating section integrated onto said substrate;
and
_____ a reflective surface associated with said piezoelectric/electrostrictive film ~~type~~ element.
3. (Currently Amended) The apparatus according to claim 2, wherein said substrate of ~~the said~~ piezoelectric/electrostrictive film ~~type~~ element ~~has~~ comprises a relatively-thin and, flexible sheet section and a peripheral section surrounding said sheet section, said peripheral section being relatively rigid and thicker than said sheet section, and wherein said piezoelectric/electrostrictive operating section is arranged on said sheet section of ~~the~~ said substrate.
4. (Currently Amended) The apparatus according to claim 3, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on said sheet section;
a piezoelectric/electrostrictive layer arranged on said first electrode;
a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and
wherein said reflective surface ~~is formed by~~ comprises a layer ~~that is~~ arranged on said second electrode.

5. (Currently Amended) The apparatus according to claim 3, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on one face of said sheet section;
a piezoelectric/electrostrictive layer arranged on said first electrode;
a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and
wherein said reflective surface ~~is formed by~~ comprises a layer ~~that is~~ arranged on the other face of said sheet section.

6. (Currently Amended) The apparatus according to claim 3, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on said sheet section;
a piezoelectric/electrostrictive layer arranged on said first electrode; and
a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode, wherein said second electrode ~~forms~~ comprises said reflective surface.

7. (Currently Amended) The apparatus according to claim 1, further comprising at least one of:

a first optical system arranged in an optical path between said laser beam source and said laser beam diameter adjusting means; and
a second optical system arranged in an optical path between said laser beam reflecting direction controlling means and said recording means.

8. (Currently Amended) An apparatus for outputting a laser beam comprising:
a laser beam source;
laser beam diameter adjusting means for adjusting a diameter of a beam incident from said laser beam source;
laser beam reflecting direction controlling means for controlling a reflecting direction of ~~the said~~ beam incident from said laser beam diameter adjusting means; and
recording means for recording information data in accordance with said diameter of the beam incident from said laser beam ~~reflection~~ reflecting direction controlling means;
wherein said laser beam diameter adjusting means comprises:
_____ a piezoelectric/electrostrictive film type-element comprising:
_____ a substrate;
_____ a piezoelectric/electrostrictive operating section integrated onto said substrate; and
_____ a reflective surface associated with said piezoelectric/electrostrictive film type-element.
9. (Currently Amended) The apparatus according to claim 8, wherein said substrate of ~~the said~~ piezoelectric/electrostrictive film type-element has a relatively thin and, flexible sheet section and a peripheral section surrounding said sheet section, said peripheral section being relatively rigid and thicker than said sheet section, and wherein said piezoelectric/electrostrictive operating section is arranged on said sheet section of ~~the said~~ substrate.
10. (Currently Amended) The apparatus according to claim 9, wherein said piezoelectric/electrostrictive operating section comprises:
a first electrode arranged on said sheet section;
a piezoelectric/electrostrictive layer arranged on said first electrode;
a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and
wherein said reflective surface ~~is formed by~~ comprises a layer ~~that is~~ arranged on said second electrode.

11. (Currently Amended) The apparatus according to claim 9, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on one face of said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode;

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode; and

wherein said reflective surface ~~is formed by~~ comprises a layer ~~that is~~ arranged on the other face of said sheet section.

12. (Currently Amended) The apparatus according to claim 9, wherein said piezoelectric/electrostrictive operating section comprises:

a first electrode arranged on said sheet section;

a piezoelectric/electrostrictive layer arranged on said first electrode; and

a second electrode arranged on said piezoelectric/electrostrictive layer, said second electrode being capable of applying an electric field to said piezoelectric/electrostrictive layer in cooperation with said first electrode, wherein said second electrode ~~forms~~ comprises said reflective surface.

13. (Currently Amended) The apparatus according to claim 8, further comprising at least one of:

a first optical system arranged in an optical path between said laser beam source and said laser beam diameter adjusting means; and

a second optical system arranged in an optical path between said laser beam reflecting direction controlling means and said recording means.